

Image

1753



03560.002983

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
HIROSHI ECHIZEN ET AL.) : Examiner: Steven H. Versteeg
Application No.: 10/050,787) : Group Art Unit: 1753
Filed: January 18, 2002) :
For: SPUTTERING METHOD AND)
SPUTTERING APPARATUS : March 26, 2004

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments:

In response to the Office Action dated January 21, 2004, kindly amend the above-identified application as follows: